



IFW

Attorney Docket no: 0553-322.01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Shunpei YAMAZAKI)
)
Serial No.: 10/706,357)
)
Filed: November 12, 2003)
)
For: Thermal Treatment Equipment And Method)
For Heat-Treating)
)
Examiner: A. Ghyka)
)
Art Unit: 2812)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:
Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450 on

February 18, 2005
(Date of Deposit)

Shannon Wallace

Name of applicant, assignee, or Registered Rep.

Shannon Wallace 2/18/05
Signature Date

RESPONSE (C) TO OFFICE ACTION

Sir:

Applicant has the following Response to the Office Action of November 18, 2004
in the above-identified application.

Claim Rejections - 35 USC §102

In the Office Action, the Examiner rejects Claims 28, 31-32 and 36 under 35 USC §102(e) as being anticipated by Yamazaki et al. (US 6,140,667). This rejection is respectfully traversed.

More specifically, independent Claims 28 and 32 recite the steps of cooling the crystalline semiconductor film by applying a first cooling gas after the crystallizing, and